

ABSTRACT OF THE DISCLOSURE

A stage apparatus includes a base having a reference surface, a moving unit which moves along the reference surface, a static bearing which is provided in the moving unit and which supports the moving unit such that the moving unit can move along the reference surface, and a temperature controller which is provided in the moving unit and which controls the temperature of gas supplied to the static bearing. In the stage apparatus, air fluctuation in the measurement area of interferometers due to gas exhausted from the static bearing and/or distortion caused by heat transmitted to a retainer of a target is suppressed, and the stage positioning accuracy is thereby increased.